



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Re application of:

K. Hashimoto et al.

Application No.: 10/028,429

Filed: December 28, 2001

Group Art Unit: 2823

Examiner: K. Nguyen

Docket No.: 107317-00039

SEP 16 2003  
TECHNICAL CENTER 2000

For: DRY ETCHING WITH REDUCED DAMAGE TO MOS DEVICE

**AMENDMENT UNDER 37 C.F.R. § 1.116**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

September 16, 2003

Sir:

**INTRODUCTORY COMMENTS**

In reply to the Office Action mailed June 16, 2003, please consider the following remarks: